



# Impact of thermal coupling effects on the digital and analog figures of merit of UTBB SOI MOSFET pairs

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## ABSTRACT

This work studies the thermal cross-coupling between two side-by-side UTBB (ultra-thin body and ultra-thin BOX) fully-depleted Silicon-on-Insulator (FD-SOI) MOSFETs. Due to the operation (i.e. heating) of the neighbor (actuator) device, the temperature of the measured device increases, which deteriorates its electrical parameters. This degradation is studied as a function of the bias applied to (i.e. power dissipated by) the neighbor device on main digital ( $SS$ ,  $V_{Th}$  and  $I_{on}/I_{off}$ ) and analog ( $g_m$ ,  $g_m/I_d$  and  $A_v$ ) Figures of Merit as well as the 2nd and 3rd order harmonic distortions ( $HD_2$  and  $HD_3$ ).

## 1. Introduction

Enormous progress in the semiconductor industry has been made during the two last decades to enable the continuous technology downscaling to 20 nm and beyond. From the device architecture point of view, UTBB (ultra-thin body and ultra-thin BOX) fully-depleted (FD) Silicon-on-Insulator (SOI) technology is widely considered as one of the main contenders for device downscaling [1]. Indeed, in addition to its outstanding electrostatic control, very low mismatch, high performance in terms of low-power, high-speed, it also features attractive analog and RF figures of merit (FoMs) [2]. However, in spite of its numerous advantages, comparative studies [3,4] of self-heating (SH) reported that the lower thermal conductivity of the buried oxide w.r.t silicon makes it more subject to self-heating than their bulk counterparts, which can affect both device performance and RF figures of merit. Studying device self-heating and thermal cross-coupling between neighbor devices [5,6] is therefore crucial, especially for applications such as current mirrors [7] which strongly rely on matching, quantum computing [8] or 3D resistive random access memory (RRAM) [9], whose proper functioning can be greatly impacted by these unwanted heating sources.

In our previous work [10], the degradation of the characteristics of a UTBB FD-SOI MOSFET caused by the heat originating from a neighbor device operation was shown. Temperature rise up to 14 K was found due a neighbor device biased in strong inversion and saturation. This work extends the previous analysis by studying the impact of thermal cross-

coupling on the digital and analog figures of merit (FoM) through DC measurements.

The paper is structured as follows: Section 2 describes the geometry and particularities of the devices under test. In Section 3, the impact of the thermal cross-coupling effect is studied on (i)  $I_d$ - $V_{GS}$  characteristics, (ii) digital and (iii) analog figures of merit. 2nd and 3rd order harmonic distortions ( $HD_2$  and  $HD_3$ ) are extracted as well based on DC measurements.

## 2. Experimental details

The devices used in this study are fabricated by an industrial FD-SOI CMOS process. They consist of nMOSFETs featuring a gate length below 30 nm and a single finger of 10  $\mu\text{m}$  width. The final buried oxide (BOX) and the SOI film thicknesses are in the order of 20–25 nm and 6–7 nm, respectively. In order to better demonstrate the thermal cross-coupling effect between neighbor devices representative of analog/RF circuits, very wide single finger transistors were designed, and then placed as close as possible according to the design rules of the process fabrication.

Fig. 1 shows a schematic cross-section of two transistors placed side-by-side, parallel to each other, and spaced by distances  $L_{G-G}$  from gate-to-gate and  $L_{D-S}$  from drain-to-source, where  $L_{G-G} = 312$  nm and  $L_{D-S} = 164$  nm.

In order to bring these devices as close as possible together while still meeting the design rule checks (DRCs) of the Process Design Kit (PDK),

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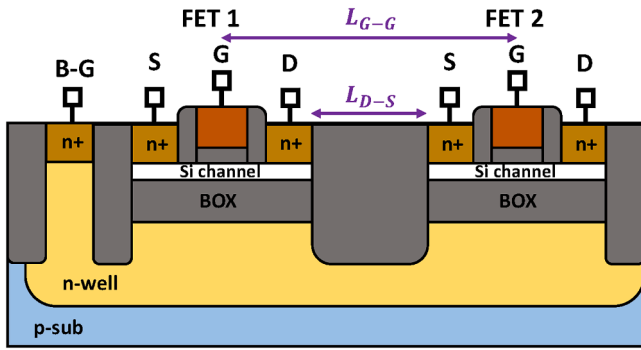


Fig. 1. Schematic cross-section of two side-by-side FD-SOI nMOSFETs spaced by distances  $L_{G-G}$  from gate-to-gate and  $L_{D-S}$  from drain-to-source (not to scale).

both devices have to share the same back-gate connection. Their back-gate (B-G) accesses are thus electrically connected together through the n-well region below the BOX. In this paper, a back-gate bias of  $V_{BG} = 0$  V was applied during all measurements.

One should note that RF devices tend to have very wide geometries with multiple fingers of several  $\mu\text{m}$  width in parallel above a common back-gate like the structure shown in Fig. 1.

### 3. Results and discussion

In this section, the degradation of the key electrical parameters of device 1 caused by the operation of device 2 is studied as a function of the different operation conditions of device 2. First, the impact of the thermal cross-coupling effect is evidenced on  $I_d$ - $V_{GS}$  characteristics. Digital figures of merit (FoMs) are then computed and analyzed as a function of the bias applied (i.e. power dissipated by) the neighbor device. Finally, the same study is conducted for analog FoMs.

Measurements presented in this section were done on three dies (not shown) to confirm the observed trends. Another important note is that the observed variations of the output characteristics due to thermal coupling are comparable to process variations but: (i) they will add upon the process variations leading to even more transistor mismatch in the technology; (ii) their physical origin is different meaning that distinct physical-based models are required; (iii) at cryogenic temperature, the impact of thermal coupling effects could be larger than at room temperature.

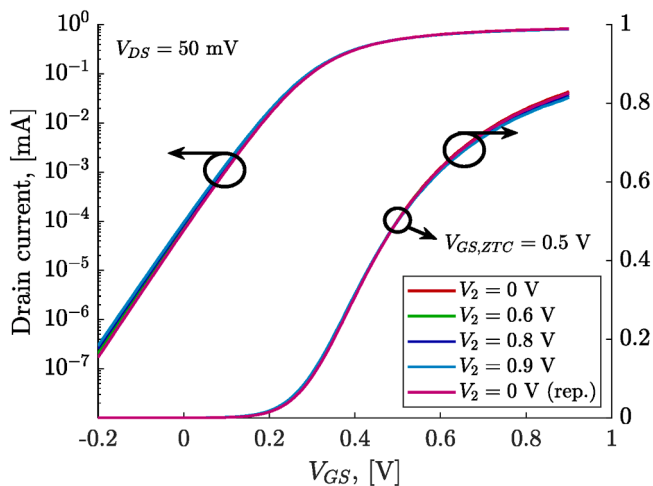


Fig. 2. Drain current  $I_d$  of FET 1 vs gate voltage  $V_{GS}$  in linear regime at  $V_{DS} = 50$  mV when FET 2 is under different bias conditions.

#### 3.1. $I_d$ - $V_{GS}$ characteristics

Fig. 2 shows  $I_d$ - $V_{GS}$  characteristic of device 1 biased in a linear regime at  $V_{DS} = 50$  mV when device 2 is biased in cold FET mode ( $V_2 = V_{GS2} = V_{DS2} = 0$  V) and in different operation conditions in saturation and strong inversion regimes ( $V_2 = 0.6, 0.8$  and  $0.9$  V). In subthreshold regime, one notes that the off-state current defined at  $V_{GS} = 0$  V increases with  $V_2$  whereas in inversion regime, the on-state current defined at  $V_{GS} = 0.8$  V decreases with  $V_2$ . The key bias point in between these two opposite behaviors with respect to temperature ( $V_2$  variations translate into temperature variations of device 1) is the zero-temperature coefficient (ZTC) point. This bias point corresponds to the gate voltage  $V_{GS}$  at which the drain current remains constant with respect to temperature. This phenomenon is due to the fact that the mobility degradation and threshold voltage shift with temperature effects compensate each other at that particular bias point. From Fig. 2, the ZTC point is  $V_{GS,ZTC} = 0.5$  V in linear regime. For  $V_{GS}$  lower than  $V_{GS,ZTC}$ , the ZTC the threshold voltage shift predominates and therefore,  $I_d$  increases with temperature, while at  $V_{GS}$  higher than  $V_{GS,ZTC}$ , mobility degradation is dominant and  $I_d$  decreases with temperature rise.

In order to check the repeatability of the measurements, the electrical parameters of device 1 were measured again with device 2 in a cold FET mode ( $V_2 = 0$  V (rep.)) after the measurements at  $V_2 = 0.9$  V. One can observe in Fig. 3 that the drain current does go back to its initial value by overlapping the curve at  $V_2 = 0$  V when the stressing conditions (power dissipated by device 2) are removed. For the purpose of clarity, all plots in the next subsections do not include  $V_2 = 0$  V (rep.) because no noticeable degradation of the device occurred during the measurement procedure.

As shown in Fig. 4,  $I_d$ - $V_{GS}$  characteristic of device 1 biased at  $V_{DS} = 800$  mV displays the same trend with respect to the bias applied to device 2 ( $V_2$ ). In strong inversion and saturation regimes of device 1, the current variations of device 1 with temperature are however lesser because the relative temperature increase is lower due to the own self-heating of device 1.

From our preliminary findings [10] shown in Fig. 5, a temperature rise up to  $\sim 14$  K was observed when a neighbor device was biased in strong inversion and saturation regime at  $V_2 = 1$  V (corresponding to a dissipated power of 9 mW). The detailed procedure to estimate the temperature increase based on hot chuck measurements is described in [10].

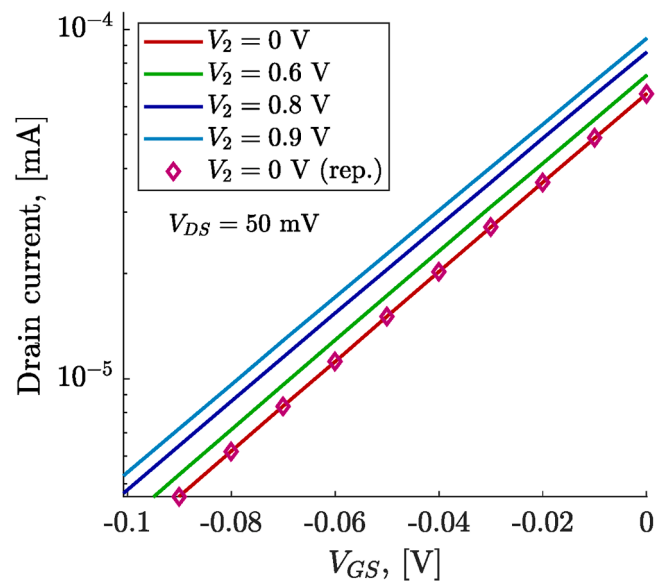


Fig. 3. Drain current  $I_d$  of FET 1 vs gate voltage  $V_{GS}$  at  $V_{DS} = 50$  mV when FET 2 is under different bias conditions (zoom in the subthreshold region).

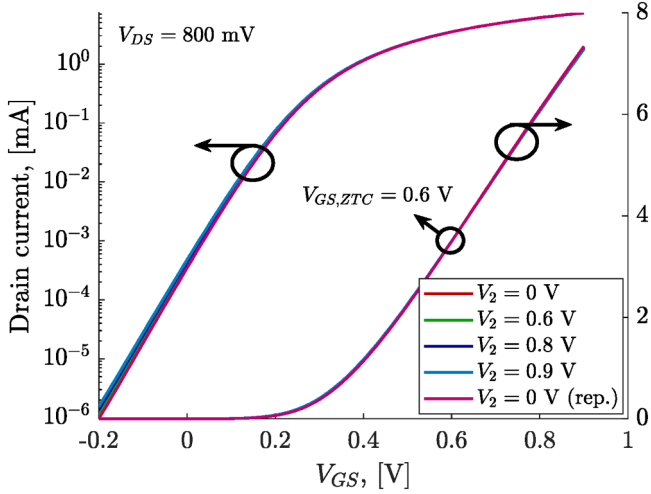


Fig. 4. Drain current  $I_d$  of FET 1 vs gate voltage  $V_{GS}$  in saturation regime at  $V_{DS} = 800$  mV when FET 2 is under different bias conditions.

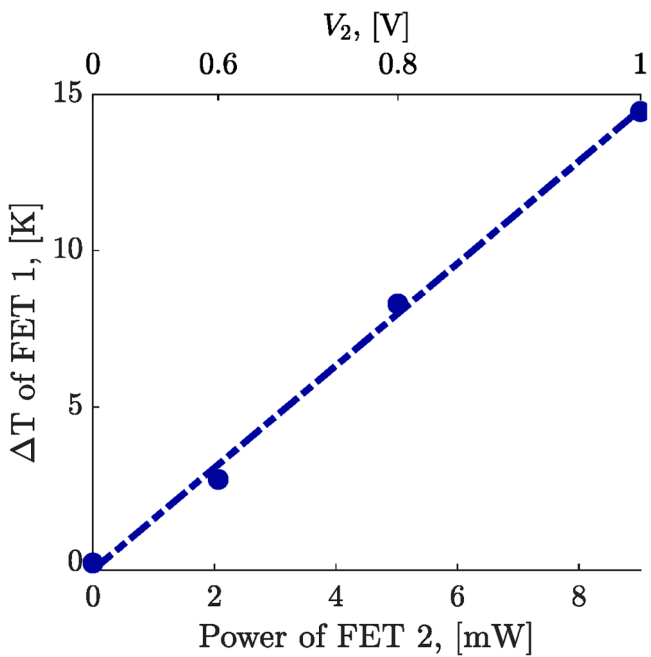


Fig. 5. Relative temperature increase  $\Delta T$  of FET 1 (extracted at  $I_d = 10^{-7}$  A and  $V_{DS1} = 50$  mV) vs dissipated power of FET 2 [10].

In this study, the maximum dissipated power of the neighbor device is 6.37 mW (at  $V_2 = 0.9$  V), which corresponds to an estimated temperature increase of  $\Delta T = \sim 10$  K.

### 3.2. Digital FoMs

Fig. 6a shows the subthreshold swing (SS) characteristic of device 1 at  $V_{DS} = 50$  mV for different  $V_2$ . The subthreshold swing is computed from  $I_d$ - $V_{GS}$  characteristic (Fig. 2) as follows:  $SS = \partial V_{GS} / \partial(\log(I_d))$ . The different bias conditions of device 2, namely  $V_2 = 0, 0.6, 0.8$  and  $0.9$  V, correspond to dissipated powers of 0, 1.89, 4.42, 6.37 mW, respectively. A linear increase of SS from 79.31 to 81.71 mV/dec vs the power of device 2 is observed in Fig. 6b, demonstrating the sensibility to thermal coupling effects.

The second derivative method is used to extract the threshold voltage  $V_{Th}$  [11]. As shown in Fig. 7, the threshold voltage reduction with the

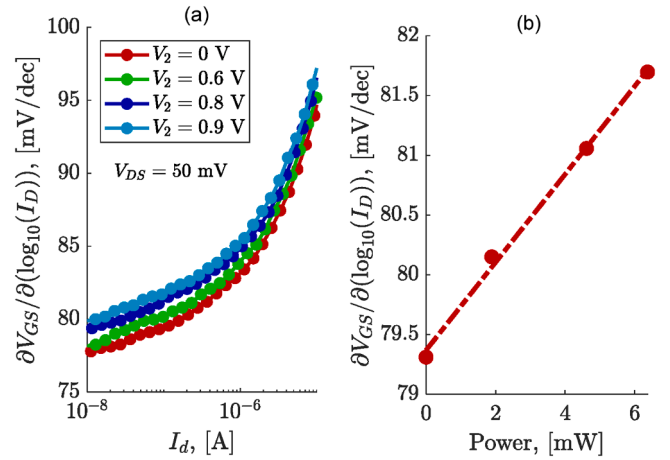


Fig. 6. (a)  $\partial V_{GS} / \partial(\log(I_d))$  vs  $I_d$  at  $V_{DS} = 50$  mV when FET 2 is under different bias conditions, and (b)  $\partial V_{GS} / \partial(\log(I_d))$  at  $I_d = 10^{-7}$  A vs dissipated power of FET 2, when FET 1 is biased at  $V_{DS} = 50$  mV.

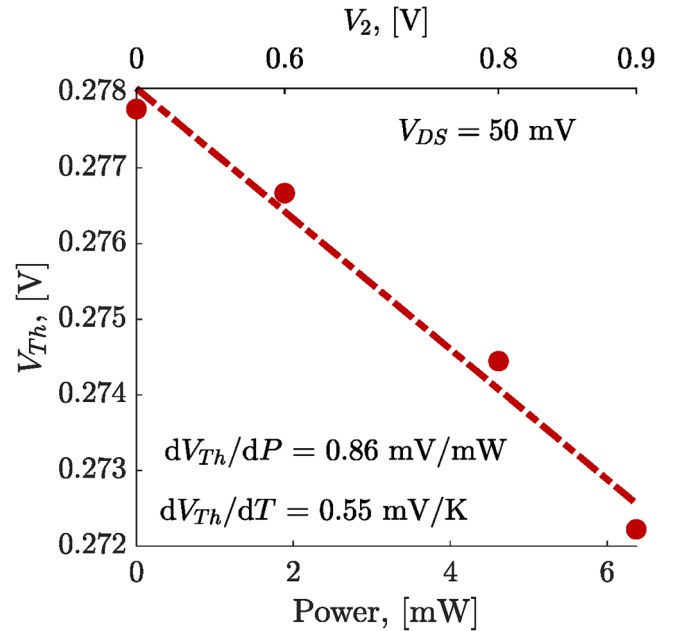


Fig. 7. Threshold voltage  $V_{Th}$  of FET 1 vs dissipated power of FET 2, when FET 1 is biased at  $V_{DS} = 50$  mV.

power of device 2 is 0.86 mV/mW. This value can be referred to the typical 0.6 mV/K slope observed in advanced technologies with ultra-thin bodies like FD-SOI and FinFETs [12]. Indeed, based on the results of Fig. 5 (from [10]), the temperature of the measured device is estimated to increase by  $\Delta T = \sim 10$  K when the neighbor device dissipates 6.37 mW (at  $V_2 = 0.9$  V), giving a ratio  $\Delta T / \Delta P \approx 1.57$  K/mW. The threshold voltage reduction with respect to temperature can then be computed as  $dV_{Th} / dT = dV_{Th} / dP \times \Delta P / \Delta T = 0.55$  mV/K, which is in agreement with the typical 0.6 mV/K slope.

It is worth pointing out that the relationship between temperature and power is only valid if the temperature is linearly dependent on the dissipated power,  $\Delta T = R_{th}P$ .

Based on the results in [13],  $R_{th}$  can be considered constant to the first order in the temperature range of interest. However, this approximation cannot be made at low temperature such as in cryogenic environment.

Another important digital figure of merit is the  $I_{On} / I_{Off}$  ratio where  $I_{On}$

is here defined as the on-state current measured at  $V_{GS} = 800$  mV,  $V_{DS} = 800$  mV and  $I_{off}$  is defined as the off-state current measured at  $V_{GS} = 0$  mV,  $V_{DS} = 800$  mV. As shown in Fig. 8, a  $\sim 30\%$  reduction of  $I_{on}/I_{off}$  ratio is observed when device 2 dissipates 6.37 mW (at  $V_2 = 0.9$  V).

This reduction of the  $I_{on}/I_{off}$  ratio is strongly related to the increase of  $I_{off}$ , changing from  $0.35 \mu\text{A}$  at  $V_2 = 0$  V to  $0.48 \mu\text{A}$  at  $V_2 = 0.9$  V as observed in Fig. 9a. Therefore, the power consumption of FET 1 in off-state ( $I_{off} \times V_{DS}$ ) increases by a significant  $\sim 30\%$  when device 2 operates at  $V_2 = 0.9$  V, as presented in Fig. 9b.

### 3.3. Analog FoMs

$g_m$ - $V_{GS}$  plot is presented in Fig. 10a for different biases applied to device 2 and the corresponding degradation of the  $g_m$  peak is 1.4% as observed in Fig. 10b. This small degradation can be explained by the temperature variations of device 1 caused by the operation of device 2 (i. e. 14 K when device 2 dissipates 9 mW [10]) and thus the mobility reduction.

Next to that,  $g_m/I_d$  as a function of  $I_d$  is a very useful characterization approach for assessing the gain and frequency potential performance in analog applications [13–16]. Fig. 11a shows  $g_m/I_d$  vs  $I_d$  plot at  $V_{DS} = 800$  mV. By taking  $g_m/I_d$  at  $I_d = 10^{-7}$  A (in weak inversion regime) for different  $V_2$ , one can see in Fig. 11b that  $g_m/I_d$  decreases linearly with the dissipated power of device 2 from  $39.6$  to  $38.2 \text{ V}^{-1}$  (3.5%). This trend is inversely proportional to the subthreshold swing. It is worth mentioning that baseband applications, requiring high gain and precision, therefore favor device operation in weak inversion regime whereas high-frequency applications, requiring high drive current, favor device operation in strong inversion regime [14].

In addition to provide a fair comparison between devices,  $g_m/I_d$  can also be fixed at a certain value and the corresponding  $I_d$  variations can be extracted. Typical  $g_m/I_d$  values are  $5 \text{ V}^{-1}$  and  $10 \text{ V}^{-1}$  because they correspond to mid- and strong inversion, respectively. Fig. 12a and 12b show  $I_d$  vs dissipated power in FET 2 at  $g_m/I_d = 5 \text{ V}^{-1}$  and  $10 \text{ V}^{-1}$ , respectively. One notices that  $I_d$  at both  $g_m/I_d$  values follows a decreasing trend, similarly to  $g_m$  (Fig. 10b), which is mainly related to the mobility degradation.

From  $I_d$ - $V_{DS}$  characteristics (not shown), the output conductance  $g_d$  is calculated as  $dI_d/dV_{DS}$ .  $g_d$  vs  $V_{DS}$  plot at  $V_{GS} = 0.8$  V is shown in Fig. 13 for different bias conditions of device 2 ( $V_2$ ). At  $V_{DS} = V_{GS} = 0.8$  V, one

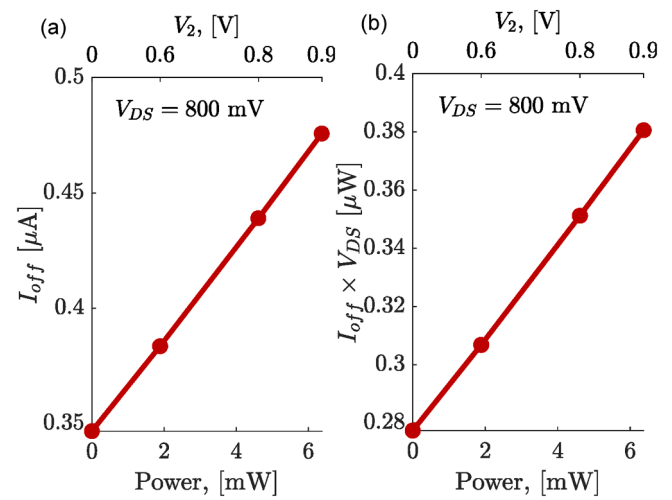


Fig. 9. (a)  $I_{off}$  and (b)  $I_{off} \times V_{DS}$  of FET 1 vs dissipated power of FET 2, when FET 1 is biased at  $V_{DS} = 800$  mV.

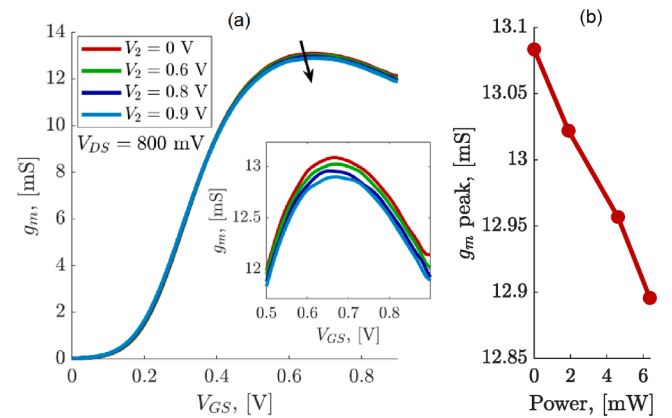


Fig. 10. (a)  $g_m$  of FET 1 vs gate voltage  $V_{GS}$  at  $V_{DS} = 800$  mV when FET 2 is under different bias conditions, and (b) its corresponding variation of  $g_m$  peak of FET 1 vs dissipated power of FET 2.

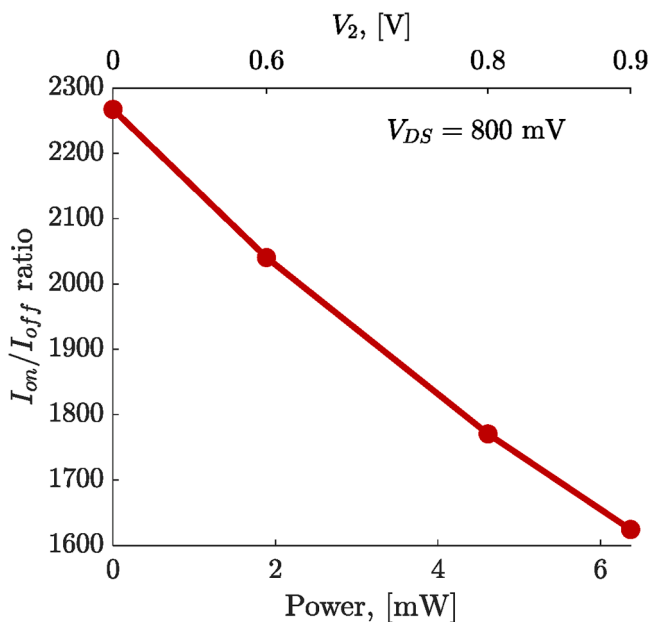


Fig. 8.  $I_{on}/I_{off}$  ratio of FET 1 vs dissipated power of FET 2, when FET 1 is biased at  $V_{DS} = 800$  mV.

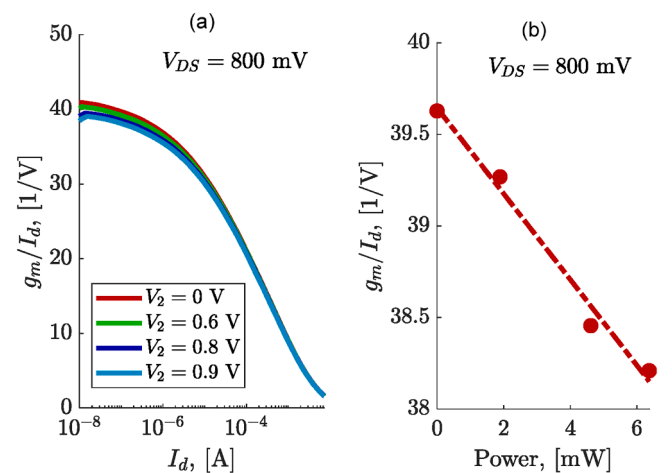


Fig. 11. (a)  $g_m/I_d$  of FET 1 vs  $I_d$  plot at  $V_{DS} = 800$  mV when FET 2 is under different bias conditions, and (b)  $g_m/I_d$  of FET 1 at  $I_d = 10^{-7}$  A vs dissipated power of FET 2, when FET 1 is biased at  $V_{DS} = 800$  mV.

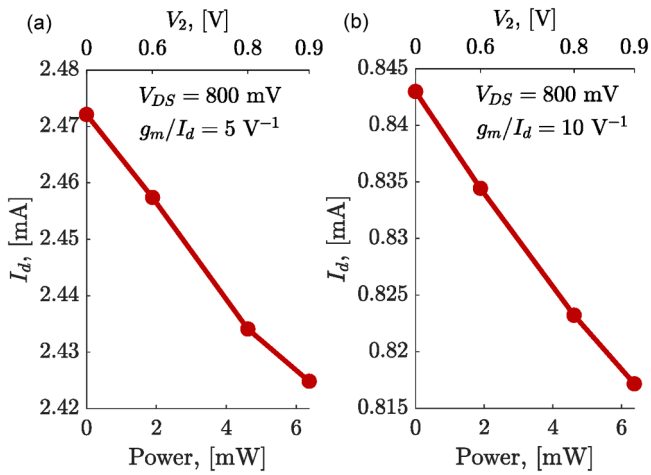


Fig. 12.  $I_d$  of FET 1 extracted at (a)  $g_m/I_d = 5 \text{ V}^{-1}$  and (b)  $g_m/I_d = 10 \text{ V}^{-1}$  vs dissipated power of FET 2, when FET 1 is biased at  $V_{DS} = 800 \text{ mV}$ .

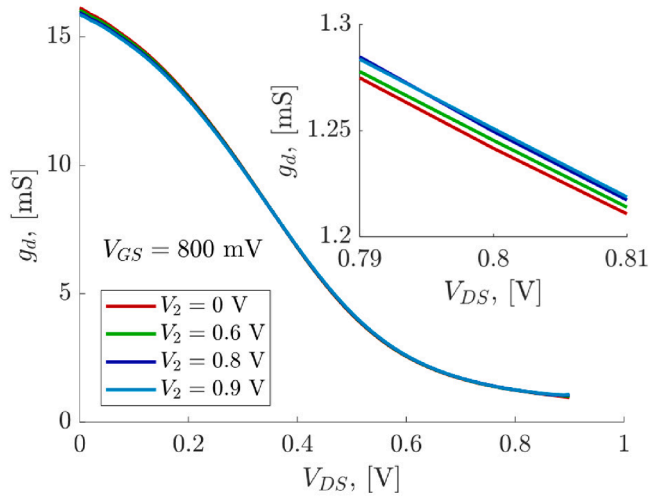


Fig. 13.  $g_d$  of FET 1 vs drain voltage  $V_{DS}$  at  $V_{GS} = 800 \text{ mV}$  when FET 2 is under different bias conditions.

observes that the  $g_d$  variations with  $V_2$  remain rather limited, with a maximum increase of 0.8% from  $V_2 = 0 \text{ V}$  to  $V_2 = 0.9 \text{ V}$  (inset of Fig. 13).

Another key analog FoM of any MOSFET is its intrinsic voltage gain  $A_v$  computed as  $A_v = g_m/g_d$ , where  $g_m$  is the transconductance and  $g_d$  is the output conductance. By plotting  $g_m$  vs  $A_v$ , one can quickly assess device performance and compare different biases or temperature conditions [12]. Both  $g_m$  and  $A_v$  are desired to be as high as possible (i.e. upper right corner of the plot). Fig. 14 shows  $g_m - A_v$  metric of FET 1 at two different biases,  $V_{GS1} = V_{DS1} = 0.6 \text{ V}$  and  $V_{GS1} = V_{DS1} = 0.8 \text{ V}$  when  $V_2$  is varied from 0 to 0.9 V. One first notices that the voltage gain at  $V_{GS} = V_{DS} = 0.6 \text{ V}$  is higher than at  $V_{GS} = V_{DS} = 0.8 \text{ V}$  but the transconductance is lower. This is because the output conductance  $g_d$  at  $V_{GS} = V_{DS} = 0.6 \text{ V}$  is lower than at  $V_{GS} = V_{DS} = 0.8 \text{ V}$  (not shown). When device 2 (i.e. heating device) is powered on, the voltage gain  $A_v$  at both  $V_{GS} = V_{DS} = 0.6$  and  $0.8 \text{ V}$  degrade by shifting toward the bottom left of the plot. The decrease in  $g_m$  (and  $A_v$ ) can be correlated with Fig. 10a.

In order to assess non-linearities, the first, second and third derivatives of  $I_d - V_{GS}$  characteristics of device 1 were computed as follows:  $g_m = dI_d/dV_{GS}$ ;  $g_{m2} = d^2I_d/dV_{GS}^2$ ;  $g_{m3} = d^3I_d/dV_{GS}^3$ . One then defines the  $K_n = 1/n!d^nI_d/V_{GS}^n$  factors. The second and third order harmonic distortions of a memoryless circuit can be calculated using a Taylor expansion [17] as  $HD_2 = A/2|K_2/K_1|$  and  $HD_3 = A^2/4|K_3/K_1|$ , where  $A$  would be the AC amplitude of the input sinusoidal signal. A low signal

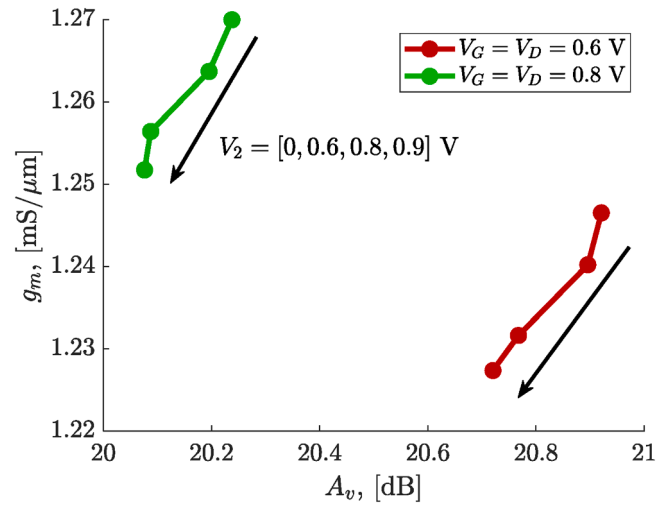


Fig. 14.  $g_m - A_v$  metric of FET 1 biased at  $V_{GS} = V_{DS} = 0.6 \text{ V}$  and  $V_{GS} = V_{DS} = 0.8 \text{ V}$  when FET 2 is under different bias conditions ( $V_2$ ).

amplitude  $A$  of  $0.05 \text{ V}$  [18] is chosen such that the Taylor expansion remains valid.

Fig. 15 shows  $g_m$  vs  $I_d$  curves for different bias conditions of device 2 ( $V_2$ ). One notes that the  $g_m$  peak reduces with increasing  $V_2$  (as in Fig. 10b) but more importantly, that  $g_m$  at  $V_2$  greater than  $0 \text{ V}$  is lower than  $g_m$  at  $V_2 = 0 \text{ V}$  over the whole drain current  $I_d$  range, due to mobility reduction with temperature.

Fig. 16 shows  $g_{m2}$  vs  $I_d$  curves for different bias conditions of device 2 ( $V_2$ ), where the critical region is around  $I_d = 0.5 \text{ mA}$ . Indeed, at this current,  $g_{m2}$  displays the strongest dependency on  $V_2$  with  $g_{m2}$  peaking above  $40 \text{ mS/V}$  because this region lies in the vicinity of  $V_{Th}$ .

In practice, the 2nd and 3rd order harmonic distortions are more important than the derivatives  $g_{m2}$  and  $g_{m3}$  by themselves. Figs. 17 and 18 show respectively  $HD_2$  and  $HD_3$  vs  $I_d$  for various  $V_2$ . One can see in Fig. 17 that although  $HD_2$  is minimized between  $I_d = 4 \text{ mA}$  and  $5 \text{ mA}$ , it is also the most sensitive part of  $HD_2$  with respect to  $V_2$  (equivalent to temperature). Above  $I_d = 1 \text{ mA}$ ,  $HD_3$  is however relatively independent of  $V_2$  and with values under  $-55 \text{ dB}$  as shown in Fig. 18.

If circuit designers want to avoid  $HD_2$  degradation caused by the operation of a neighbor FET, then they need to avoid a bias point around  $4.4 \text{ mA}$ , where  $HD_2$  can be degraded by  $\sim 10 \text{ dB}$  when FET 2 is at  $V_2 =$

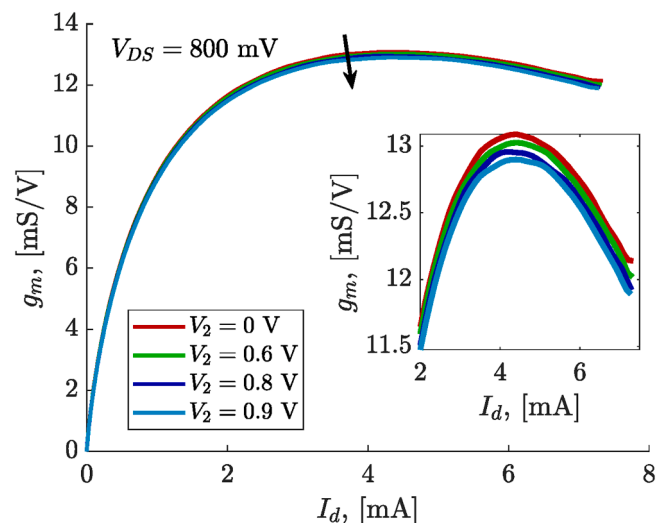


Fig. 15.  $g_m$  of FET 1 vs  $I_d$  at  $V_{DS} = 800 \text{ mV}$  when FET 2 is under different bias conditions.

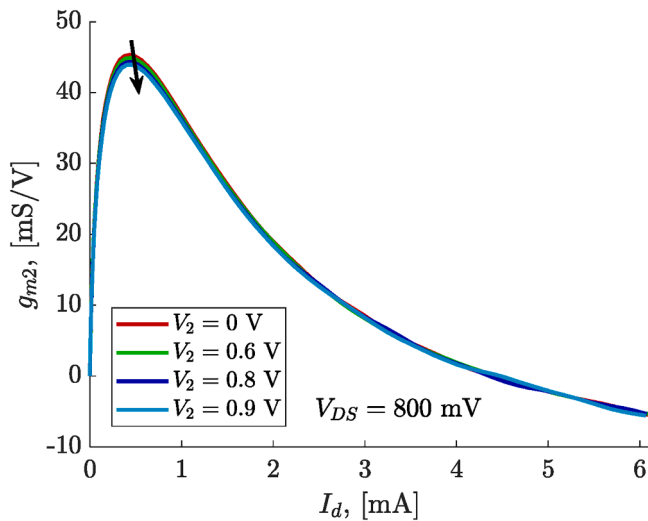


Fig. 16.  $g_{m2}$  of FET 1 vs  $I_d$  at  $V_{DS} = 800$  mV when FET 2 is under different bias conditions.

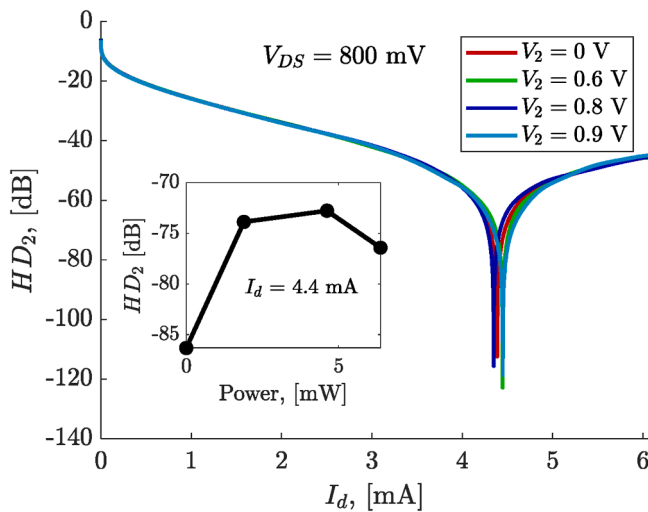


Fig. 17.  $HD_2$  of FET 1 as a function of  $I_d$  at  $V_{DS} = 800$  mV when FET 2 is under different bias conditions.  $A = 0.05$  V.

0.9 V (inset of Fig. 17).

#### 4. Conclusion

In this work, the degradation of the device characteristics caused by the heat originated from a neighbor device operation was studied. The impact of the thermal coupling was demonstrated on digital ( $SS$ ,  $V_{Th}$  and  $I_{on}/I_{off}$ ) and analog ( $g_m$ ,  $g_m/I_d$  and  $A_v$ ) parameters as well as the 2nd and 3rd order harmonic distortions ( $HD_2$  and  $HD_3$ ). The degradation due to the bias applied to (i.e. power dissipated by) the neighbor device was evidenced on all the parameters. However, overall variations remain limited with a maximum of 30% increase in  $I_{off}$  when the neighbor device is operated at the maximum bias of 0.9 V, hence dissipating 6.37 mW of power, leading to an estimated increase of temperature in device 1 of  $\sim 10$  K.

#### Declaration of Competing Interest

The authors declare that they have no known competing financial interests or personal relationships that could have appeared to influence the work reported in this paper.

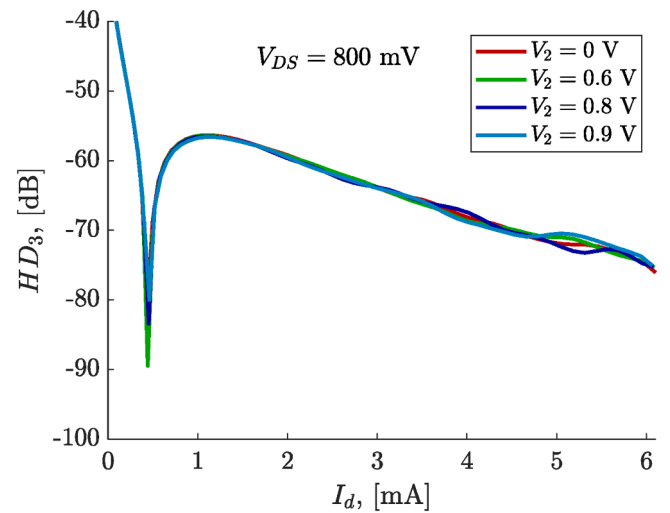


Fig. 18.  $HD_3$  of FET 1 as a function of  $I_d$  at  $V_{DS} = 800$  mV when FET 2 is under different bias conditions.  $A = 0.05$  V.

#### Data availability

The authors do not have permission to share data.

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#### References

- [1] N. Planes et al., ‘28nm FDSOI technology platform for high-speed low-voltage digital applications’, 2012 Symposium on VLSI Technology (VLSIT), 2012, doi: 10.1109/VLSIT.2012.6242497.
- [2] S. Makovejev et al., ‘Wide frequency band assessment of 28 nm FDSOI technology platform for analogue and RF applications’, in 2014 15th International Conference on Ultimate Integration on Silicon (ULIS), Apr. 2014, pp. 53–56. doi: 10.1109/ULIS.2014.6813904.
- [3] Makovejev S, Planes N, Haond M, Flandre D, Raskin J-P, Kilchytska V. Comparison of self-heating and its effect on analogue performance in 28nm bulk and FDSOI. Solid State Electron Jan. 2016;115:219–24. <https://doi.org/10.1016/j.sse.2015.08.022>.
- [4] B. K. Esfeh, V. Kilchytska, N. Planes, M. Haond, D. Flandre, and J.-P. Raskin, ‘Comparative study of parasitic elements on RF FoM in 28 nm FD SOI and bulk technologies’, in 2015 IEEE SOI-3D-Subthreshold Microelectronics Technology Unified Conference (S3S), Oct. 2015, pp. 1–3. doi: 10.1109/S3S.2015.7333532.
- [5] Costa FJ, Doria RT, Doria RT. UTBB thermal coupling analysis in technological node level. J Integr Circ Syst Jul. 2020;15(2):1–5.
- [6] Raleva Katerina, Vasilevska Dragica. SELF-HEATING EFFECTS IN SILICON NANOSCALE MOSFET (A MULTISCALE MODELING APPROACH). J Electr Eng Technol 2018;3(1-2):31–40.
- [7] Tenbroek BM, Lee MSL, Redman-White W, Bunyan RJT, Uren MJ. Impact of self-heating and thermal coupling on analog circuits in SOI CMOS. IEEE J Solid State Circuits Jul. 1998;33(7):1037–46. <https://doi.org/10.1109/4.701253>.
- [8] Charbon E, Babaie M, Vladimirescu A, Sebastiano F. Cryogenic CMOS circuits and systems: challenges and opportunities in designing the electronic interface for quantum processors. IEEE Microw Mag Jan. 2021;22(1):60–78. <https://doi.org/10.1109/MMM.2020.3023271>.
- [9] Sun P, Lu N, Li L, Li Y, Wang H, Lv H, et al. Thermal crosstalk in 3-dimensional RRAM crossbar array. Sci Rep Aug. 2015;5(1). <https://doi.org/10.1038/srep13504>.
- [10] Vanbrabant M, Raskin J-P, Flandre D, Kilchytska V. Experimental study of thermal coupling effects in FD-SOI MOSFET. Solid State Electron Aug. 2022;194:108362. <https://doi.org/10.1016/j.sse.2022.108362>.
- [11] Wong H-S, White MH, Krutsick TJ, Booth RV. Modeling of transconductance degradation and extraction of threshold voltage in thin oxide MOSFET’s. Solid State Electron Sep. 1987;30(9):953–68. [https://doi.org/10.1016/0038-1101\(87\)90132-8](https://doi.org/10.1016/0038-1101(87)90132-8).

- [12] Kilchytska V, Md Arshad MK, Makovejev S, Olsen S, Andrieu F, Poiroux T, et al. Ultra-thin body and thin-BOX SOI CMOS technology analog figures of merit. *Solid State Electron* 2012;70:50–8.
- [13] Triantopoulos K, Casse M, Barraud S, Haendler S, Vincent E, Vinet M, et al. Self-heating effect in FDSOI transistors down to cryogenic operation at 4.2 K. *IEEE Trans Electron Devices* 2019;66(8):3498–505.
- [14] Kilchytska V, Makovejev S, Esfeh BK, Nyssens L, Halder A, Raskin J-P, et al. Extensive electrical characterization methodology of advanced MOSFETs towards analog and RF applications. *IEEE J Electron Devices Soc* 2021;9:500–10.
- [15] Kilchytska V, Neve A, Vancaille L, Levacq D, Adriaensen S, van Meer H, et al. Influence of device engineering on the analog and RF performances of SOI MOSFETs. *IEEE Trans Electron Devices* 2003;50(3):577–88.
- [16] Silveira F, Flandre D, Jespers PGA. A  $g/\text{sub } m//l/\text{sub } D/$  based methodology for the design of CMOS analog circuits and its application to the synthesis of a silicon-on-insulator micropower OTA. *IEEE J Solid State Circuits Sep.* 1996;31(9):1314–9. <https://doi.org/10.1109/4.535416>.
- [17] P. Wambacq W. *Sansen Distortion Analysis of Analog Integrated Circuits* vol. 451 1998 Springer, US Boston, MA 10.1007/978-1-4757-5003-4.
- [18] Doria RT, Cerdeira A, Raskin J-P, Flandre D, Pavanello MA. Harmonic distortion analysis of double gate graded-channel MOSFETs operating in saturation. *Microelectron J Dec.* 2008;39(12):1663–70. <https://doi.org/10.1016/j.mejo.2008.02.006>.